# 7th ESA Round Table on MNT for Space Applications

The Qualification and Market Entry of the SiREUS MEMS Coarse Rate Sensor for Space Mission Applications

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#### Content



#### The background route to SiREUS

- Teaming and UK capabilities
- Principles of operation
- Programme plan
- SiREUS configuration

#### Challenges overcome during development

- Non MEMS, qualification and manufacturing
- Characteristics of MEMS sensors
- Pre-calibration of the detector
- Product assurance of MEMS
- Results
  - In orbit performance on Cryosat-2
  - EQM testing
  - SiREUS performance achievements
- Summary
- Next steps







### The background route to SiREUS

- Presentation take to story forward from previous presentations
  - 4<sup>th</sup> MNT (2003) Overview of basic technology
  - 6<sup>th</sup> MNT (2007) Status of development and Cryosat-2 FExp
  - 7<sup>th</sup> MNT (2010) Update of product development with results
  - Development of gyro technologies by the ESA harmonisation roadmap
    - to supply reliable, low cost, coarse sensors that enable robust, simple building blocks in AOCS systems
  - Evolution of MEMS Coriolis gyro technology in the UK showed potential for spin-in to the Space sector
  - Definition of market requirements for a Coarse Rate Sensor led to a viable investment case
  - Competitive procurement won by a UK consortium of three companies.
    - MEMS Rate Sensor (MRS) development programme leads to SiREUS (<u>EU</u>ropean <u>Si</u>licon <u>R</u>ate <u>S</u>ensor)











# The development team









# **Teaming and UK Capabilities**





#### **Principles of operation**



• A planar ring structure, etched from silicon, held in a resonating state by a primary drive current.



 Angular rate is determined from the shift in the secondary current required to null the Coriolis effect.



# **Application of MEMS gyros**





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- Planar ring with 8 support legs in a vacuum cavity
- Discrete capacitor plates positioned around the ring



- Mass, stiffness, geometry and characterisation determined during precision manufacture
- Power, balancing forces and control feedback
  determined by electronic design



#### **Programme Plan**









# SiREUS – Configuration





Sensor Type Mass Power	3 axis rate sensor < 0.8kg 5.1W	
Bandwidth	10 Hz (max)	
Measurement Output Rate	2 - 20 Hz (settable), 0 Hz = no output	
Switch-on to Switch-on Change	< 10 deg/hr (with off time constraints)	
Angular Rate Bias	10 - 20 deg/hr	
Rate Bias Drift	5 - 10 deg/hr over 24 hours with ±10°C	
Scale Factor Linearity	< 2000 ppm over input range	
Angular Random Walk	0.1 - 0.2 deg/√hr	
Noise Equiv't Rate	< 1 deg/hr (defined as flicker rate)	
Interface Rad Tolerance	Analogue, RS422 100krads, 18 yr GEO	

# Several challenges overcome during the development and qualification



- Non MEMS issues
  - Power supply start-up and temperature dependency
  - · Parts supply and component obsolescence
- Rapid supply to mission
  - Lessons-learnt feedback into design from Cryosat-2 FExp development
- Environmental qualification
  - Initial thermal restriction on baseline PSU limits upper performance temperature
  - FPGA mounting at high g levels. Solved by Structural Model tests, and specification agreed with ESA

#### Manufacturing of MEMS for Space

- · Commercial performance is a long way from Space requirements
- High volume reliability and repeatability with low volume batches
- Trade-offs and design tolerances
- Design right, processes right, electronic integration right

#### Cost containment

• High reliability and ITAR free.....





# Characteristics of capacitive MEMS-based sensors

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- Move to volume production line
  - Change in performance stabilisation
- Cause / affect
  - Migration of charged species to capacitor plate surfaces





- · Initial drift in scale factor and bias on start
- Solution
  - Review of detector design and iteration of manufacturing processes
  - Refined calibration and characterisation during system integration
  - Fundamental, device and unit level management of system











#### **Pre-calibration of detector**



- Detectors are assessed for scale factor and bias stability prior to system-level calibration
  - Uncalibrated detector performance specification agreed
- Scale factor within specification of < 2000ppm</li>
- Bias within specification of 10 20 deg / hr
- Close integration with electronics provides opportunities for better performance than seen precalibration
- Further activities identified to remove even this small residual error



#### **Product assurance with MEMS**



- Agreed procurement specification
- MEMS Evaluation Flowchart adapted ESCC 2269000 and developed for Phase 3
- Development of PAD and PID for MEMS detector



Figure 9-1 Evaluation Test Programme (Chart I)

INSPECTION

Para 5.5 External Visual Inspection Para 5.6 PIND

Para 5.9 Marking and Serialisation

Hermeticit

Para 5.4 Electrical Parameters go-no-go

Radiographic Inspection

n = 106

100 % Read and Record. Para. 6 Tables 2 and 3 of Detail Specification

Para 5.2 Dimensions go-no-go

Para 5.3 Mass

Para 5.7

Para 5.8

Para. 5

100 %

100 %

100 %

100 %

100 %

100 %



#### **In-orbit performance on Cryosat-2**



- Launched 8 April 2010
- Early-build detectors, and system configured for limited functionality
  - Only X and Z axes operative
  - Known anomaly on Y axis before launch
- FExp X and Z rates verified against Star Tracker inertial measurement





#### **EQM** testing

- Physical Properties
- Functional Test
- Calibration and Check (Thermal) Tests
- Performance (Thermal and Rate) Tests
- Environmental
  - Vibration Tests
  - Shock Tests
  - Thermal Vacuum Tests
  - EMC/ESD Tests





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EX GALILEO

THERMAL VACUUM (Deg C)			$\sim$
PSU	Phase 2	Phase 3	
T min	-40	-40	
T max	+60	+75	















- At initial unit switch-on with base parameters UNCOMPENSATED
  - A = Stabilisation time in 200 mins
  - B = Quite noisy rate, but the average is well behaved
  - C = Steady output at ~20 deg/ hr

- CALIBRATED switch on post compensation
  - A = Stabilisation time in 30 mins
  - B = Less noisy rate, but the average is well behaved
  - C = Steady output at ~10 deg/ hr









• CALIBRATED unit undertaking slew manoeuvres while on rate table at 20C













#### Summary



- Assembly of UK team with ESA guidance and support
  - careful consideration of internal capabilities and those of all suppliers helps to ensure that the process 'challenges' are shared around equitably.

#### Preparing MEMS for Space

- Adaptation of terrestrial MEMS technology and processes for space-grade instruments
- Several new developments
  - Space-grade electronics to accompany the detector
  - refinement of compensation loops to obtain optimum detector performance
  - Compact housing with high environmental capability
- Delivery of FExp to Cryosat-2 programme now operational in-orbit
- Detailed design, build and test of SiREUS MEMS Qualification Model
- The MEMS detector is not standalone
  - requires close integration
  - control electronics
  - · test and calibration procedures
  - there are inevitably trade-offs to be made, for example, between the MEMS fabrication tolerances and the precision of the electronics

#### The next steps



- Post qualification upgrades
  - 1. ITAR-free PSU
    - Higher efficiency
    - Greater capability
    - · Fits within existing housing
  - 2. Replacement of FPGA by ITAR-free ASIC
    - Multi-Project Wafer approach for European-sourced ASIC

Progress

-Design Completed - EQM PSU in build

- Same package style as present FPGA
- Functionality/capability improvements available
- Further evaluation testing planned at ESA and at Astrium
- Further miniaturisation, performance improvement, integration for explorers & Smallsats...?
- SiREUS selected on Sentinel-3A/3B, Gokturk, Orbital Sciences and TechDemoSat



Progress: - PDR held with ESA - Logic review with Atmel next

Progress: - Pending







#### SiREUS – Part of the Family











#### **Contacts and acknowledgements**



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#### Acknowledgements

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